Ref #	Hits	Search Query	DBs	Default Operato r	Plural s	Time Stamp
S1	681	(702/179).CCLS.	US-PGPUB ; USPAT; USOCR	OR	OFF	2007/03/13 09:50
S2	153	(702/109,110).CCLS.	US-PGPUB ; USPAT; USOCR	OR	OFF	2007/03/13 09:50
S3	1760	(702/57,58,117).CCLS.	US-PGPUB ; USPAT; USOCR	OR	OFF.	2007/03/13 09:50
S4	426	(324/716,718).CCLS.	US-PGPUB ; USPAT; USOCR	OR	OFF	2007/03/13 09:50
S5	0	(model\$1base\$1 near monitor\$3) and (goodness near1 fit\$1)	US-PGPUB ; USPAT; USOCR	OR	ON	2007/03/13 09:51
S6	4	((manipulat\$5 calculat\$5 form\$3) with (goodness near1 (fit\$3 measur\$4 statistical\$3))) and ((semiconductor\$1 wafer\$1) with (form\$3 near process\$3))	US-PGPUB ; USPAT; USOCR	OR	ON	2007/03/13 10:10
S7	0	((manipulat\$5 calculat\$5 form\$3) with (goodness near1 (fit\$3 measur\$4 statistical\$3))) and ((semiconductor\$1 wafer\$1) with (form\$3 near process\$3)) and (independent with variable\$1)	US-PGPUB ; USPAT; USOCR	OR	ON	2007/03/13
\$8	0	(((manipulat\$5 calculat\$5 form\$3) with (goodness near1 (fit\$3 measur\$4 statistical\$3))) and ((semiconductor\$1 wafer\$1) with (form\$3 near process\$3)) and (independent with variable\$1)).clm.	US-PGPUB ; USPAT; USOCR	OR	ON	2007/03/13
S9	681	S1	US-PGPUB ; USPAT; USOCR	OR	ON	2007/03/13 10:10

S10	. 0	S4 and S1	US-PGPUB ; USPAT; USOCR	OR	ON	2007/03/13 10:10
S11	0	S2 and S4	US-PGPUB ; USPAT; USOCR	OR	ON	2007/03/13 10:10
S12	2	S4 and S3	US-PGPUB ; USPAT; USOCR	OR	ON	2007/03/13 10:32
S14	0	S12 and S6	US-PGPUB ; USPAT; USOCR	OR	ON	2007/03/13 10:10
·S15	0	S6 and S1	US-PGPUB ; USPAT; USOCR	OR	ON	2007/03/13 10:11
S16	0	S2 and S6	US-PGPUB ; USPAT; USOCR	OR	ON	2007/03/13 10:11
S17	0	S3 and S6	US-PGPUB ; USPAT; USOCR	OR	ON	2007/03/13 10:11
S18	0	S4 and S6	US-PGPUB ; USPAT; USOCR	OR	ON	2007/03/13 10:11
S19	1	"20050027476"	US-PGPUB ; USPAT; USOCR	OR.	ON	2007/03/13 10:49
S20		((goodness with fit\$1) with value\$1) same (independent with variable\$1) same ((measur\$4 actual) near1 value\$1) same (process\$3 near control\$1) same (form\$3 with (device\$1 structure\$1))	US-PGPUB ; USPAT; USOCR	OR	ON	2007/03/13 10:51
S21	1	(monitor\$3 with (process\$3 near stability)) and (fit\$3 with value\$1) and (linear\$3 with regression\$3) and (coefficient\$1 near (relat\$3 correlat\$3))	US-PGPUB ; USPAT; USOCR	OR	ON	2007/03/13 10:53

S22	1	(monitor\$3 with (process\$3	US-PGPUB	OR	ON	2007/03/13
		defect\$1 device\$1 structure\$1 wafer\$1)) and ((us\$3 usag\$3) with (goodness near (curve\$1 fit\$1) near value\$1)) and (process\$3 with control\$3 with (limit\$1 threshold\$1)) and (independent\$1 with variable\$1)	; USPAT; USOCR			10:56
S23	. 0	((monitor\$3 with (process\$3 defect\$1 device\$1 structure\$1 wafer\$1)) and ((us\$3 usag\$3) with (goodness near (curve\$1 fit\$1) near value\$1)) and (process\$3 with control\$3 with (limit\$1 threshold\$1)) and (independent\$1 with variable\$1)).clm.	US-PGPUB ; USPAT; USOCR	OR	ON	2007/03/13 10:57
S24	0	((statisticS3 near analys\$3) and (goodness near (curve\$1 fitS4))) same (process\$3 adj control\$3)	US-PGPUB ; USPAT; USOCR	OR	ON	2007/03/13 11:01
S25	0	((statisticS3 near analys\$3) and (goodness near (curve\$1 fitS4))) same (process\$3 adj control\$3) same ((calculat\$4 manipulat\$4) with (goodness near2 value\$1))	US-PGPUB ; USPAT; USOCR	OR	ON	2007/03/13 10:57
S26	0	S25 and S1	US-PGPUB ; USPAT; USOCR	OR	ON	2007/03/13 10:57
S27	0	S25 and S2	US-PGPUB ; USPAT; USOCR	OR	ON ·	2007/03/13 10:57
S28	0	S25 and S3	US-PGPUB ; USPAT; USOCR	OR	ON	2007/03/13 10:57
S29	0	S25 and S4	US-PGPUB ; USPAT; USOCR	OR	ON	2007/03/13 10:57

S30	0	((monitor\$3 with (process\$3 defect\$1 device\$1 structure\$1 wafer\$1)) same ((us\$3 usag\$3) with (goodness near (curve\$1 fit\$1) near value\$1)) same (process\$3 with control\$3 with (limit\$1 threshold\$1)) same (independent\$1 with variable\$1)).clm.	US-PGPUB ; USPAT; USOCR	OR	ON	2007/03/13 10:58
S31	0	((monitor\$3 with (process\$3 defect\$1 device\$1 structure\$1 wafer\$1)) same ((us\$3 usag\$3) with (goodness near (curve\$1 fit\$1) near value\$1)) same (process\$3 with control\$3 with (limit\$1 threshold\$1)) same (devi\$5 with sheet with resist\$4) same (independent\$1 with variable\$1)).clm.	US-PGPUB ; USPAT; USOCR	OR	ON	2007/03/13
S32	0	S31 and S1	US-PGPUB ; USPAT; USOCR	OR	ON	2007/03/13 11:00
S33	0	S31 and S2	US-PGPUB ; USPAT; USOCR	OR	ON	2007/03/13
S34	0	S31 and S3	US-PGPUB ; USPAT; USOCR	OR	ON	2007/03/13
S35	0	S31 and S4	US-PGPUB ; USPAT; USOCR	OR	ON	2007/03/13 11:00
S36	. 0	S31 and S6	US-PGPUB ; USPAT; USOCR	OR	ON	2007/03/13 11:01
S37	0	(((manipulat\$3 calculat\$3 form\$3)with (goodness nearl (fit\$3 measur\$4 statistical\$3))) and ((semiconductor\$1 wafer\$1) with (form\$3 near process\$3)))and ((statistic\$3 near analys\$3) and (goodness near (curve\$1 fit\$4))) same (process\$3 adj control\$3)	US-PGPUB ; USPAT; USOCR	OR	ON	2007/03/13 11:02

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S38	0	(((manipulat\$3 calculat\$3 form\$3)with (goodness nearl (fitS3 measur\$4 statistical\$3))) and ((semiconductor\$1 wafer\$1) with (form\$3 near process\$3)))and ((statisticS3 near analys\$3) and (goodness near (curve\$1 fitS4))) same (process\$3 adj control\$3) same (monitor\$3 with (sheet\$1 with resist\$4))	US-PGPUB ; USPAT; USOCR	OR	ON	2007/03/13 11:02
S39	0	(((manipulat\$3 calculat\$3 form\$3)with (goodness nearl (fitS3 measur\$4 statistical\$3))) and ((semiconductor\$1 wafer\$1) with (form\$3 near process\$3)))and ((statistic\$3 near analys\$3) and (goodness near (curve\$1 fit\$4))near value\$1) same (process\$3 adj control\$3) same (monitor\$3 with (sheet\$1 with resist\$4))	US-PGPUB ; USPAT; USOCR	OR	ON	2007/03/13
S40		((((manipulat\$3 calculat\$3 form\$3)with (goodness nearl (fit\$3 measur\$4 statistical\$3))) and ((semiconductor\$1 wafer\$1) with (form\$3 near process\$3))) and ((statistic\$3 near analys\$3) and (goodness near (curve\$1 fit\$4))near value\$1) same (process\$3 adj control\$3) same (monitor\$3 with (sheet\$1 with resist\$4))).clm.	US-PGPUB ; USPAT; USOCR	OR	ON	2007/03/13
S41	784	(700/109,110).CCLS.	US-PGPUB ; USPAT; USOCR	OR	OFF	2007/03/13 11:06
S42	1	((curve near fit\$3) near value\$1) and (screen\$3 with (device\$1 structure\$1)) and (defect\$1 with detect\$3)	US-PGPUB ; USPAT; USOCR	OR	ON	2007/03/13 11:08
S43	23	(curve near fitt\$3) and (process\$3 with (controL\$3 monitor\$3)) and (detect\$3 with defect\$1) and (goodness near fit\$4)	US-PGPUB ; USPAT; USOCR	OR	ON	2007/10/29 11:28

S44	1	S43 and S1	US-PGPUB ; USPAT; USOCR	OR	ON	2007/03/13 11:08
S45		S44 and S2	US-PGPUB ; USPAT; USOCR	OR	ON	2007/03/13 11:08
S47	0	S41 and S43	US-PGPUB ; USPAT; USOCR	OR	ON	2007/03/13 11:09
S48		(curve near fitt\$3) and (process\$3 with (controL\$3 monitor\$3)) and (detect\$3 with defect\$1) and ((goodness nearl (fit\$4 measur\$3)) (coefficient\$1near correlation\$1))	US-PGPUB ; USPAT; USOCR	OR	ON	2007/03/13 11:09
S50	46	(curve near fitt\$3) and (process\$3 with (control\$3 monitor\$3)) and (detect\$3 with defect\$1) and ((goodness nearl (fit\$4 measur\$3)) (coefficient\$1 near correlation\$1)) and (sheet\$1 near (resistance resistivity))	US-PGPUB ; USPAT; USOCR	OR	ON	2007/10/26 16:27
S51	1	S50 and S1	US-PGPUB ; USPAT; USOCR	OR	ON	2007/03/13 11:11
S52	0	S50 and S41	US-PGPUB ; USPAT; USOCR	OR	ON	2007/03/13 11:11
S54	1	S50 and S43	US-PGPUB ; USPAT; USOCR	OR	ON	2007/03/13 11:11
S55	0	S50 and S23	US-PGPUB ; USPAT; USOCR	OR	ON	2007/03/13 11:12

S57	0	(curve near fitt\$3) and (process\$3 With (control\$3 monitor\$3)) and (detect\$3 with defect\$1) and ((goodness near1 (fit\$4 measur\$3)) (coefficient\$1 near correlation\$1)) and (test\$3 with (structure\$1 wafer\$1)) and (model\$1 base\$1 with statistic\$3) and (form\$3 near (device\$1 structur\$3)) and ((divid\$3 divis\$3) with (parameter\$1 near sheet\$1 near resist\$4))	US-PGPUB ; USPAT; USOCR	OR	ON	2007/03/13 11:17
S58	0	((curve near fitt\$3) and (process\$3 With (control\$3 monitor\$3)) and (detect\$3 with defect\$1) and ((goodness near1 (fit\$4 measur\$3)) (coefficient\$1 near correlation\$1)) and (test\$3 with (structure\$1 wafer\$1)) and (model\$1 base\$1 with statistic\$3) and (form\$3 near (device\$1 structur\$3)) and ((divid\$3 divis\$3) with (parameter\$1 near sheet\$1 near resist\$4)) and (test\$1 near (condition\$1 environment\$1))). clm.	US-PGPUB ; USPAT; USOCR	OR	ON	2007/03/13 11:18
S60	0	S58 and S1	US-PGPUB ; USPAT; USOCR	OR	ON	2007/03/13 11:18
S61	0	S58 and S2	US-PGPUB ; USPAT; USOCR	OR	ON	2007/03/13 11:19
S62	335	(702/118).CCLS.	US-PGPUB ; USPAT; USOCR	OR	OFF	2007/03/13
S63	0	S6 and S62	US-PGPUB ; USPAT; USOCR	OR	ON	2007/03/13 11:21
S64	0	S62 and S58	US-PGPUB ; USPAT; USOCR	OR	ON	2007/03/13 11:21

S65	2	(("5574890") or ("6403389")). PN.	US-PGPUB ; USPAT; USOCR	OR	OFF	2007/03/14 11:40
S66	1	S65 and monitor\$3	US-PGPUB ; USPAT; USOCR	OR	ON .	2007/03/14 11:41
S67	2	S65 and (monitor\$3 control\$3)	US-PGPUB ; USPAT; USOCR	OR	ON	2007/03/14 11:41
S68	28	("3335340" "3974443" "4445180" "4516071" "4560583" "4722154" "4871962" "4972248" "5010029" "5561373" "5719495" "5793471" "5854097" "5857258" "5883437" "5933020" "5963784" "6019850" "6022750" "6028440" "6087189" "6291254").PN. OR ("6403389").URPN.	US-PGPUB ; USPAT; USOCR	OR	ON	2007/03/14 11:46
S69	0	(process\$3 near control\$3 and monitor\$3) same (wafer\$1 semiconductor\$1) same (best near fit\$3)	US-PGPUB ; USPAT; USOCR	OR	ON	2007/03/14 11:47
S70	21	(curve near fitt\$3) and (process\$3 With (control\$3 monitor\$3)) and (detect\$3 with defect\$1) and ((goodness near1 (fit\$4 measur\$3)) (coefficient\$1 near correlation\$1)) and (test\$3 with (structure\$1 wafer\$1)) and (model\$1 base\$1 with statistic\$3)	US-PGPUB ; USPAT; USOCR	OR	ON .	2007/03/14 11:47
S71	591	(process\$3 near control\$3 and monitor\$3) and (wafer\$1 semiconductor\$1) and (best near fit\$3)	US-PGPUB ; USPAT; USOCR	OR	ON	2007/03/14 11:48
S72	5	(process\$3 near control\$3 and monitor\$3) and (wafer\$1 semiconductor\$1) and (best near fit\$3) and (GOF\$1)	US-PGPUB ; USPAT; USOCR	OR	ON	2007/03/14 11:51

S73	18988	(GOF\$1 (best\$1fit\$3) (goodness with fit\$3)) and (monitor\$3 control\$3)	US-PGPUB ; USPAT; USOCR	OR	ON	2007/03/14 11:52
S74	508	(GOF\$1 (best\$1fit\$3) (goodness with fit\$3)) with (monitor\$3 control\$3)	US-PGPUB ; USPAT; USOCR	OR	ON	2007/03/14 11:52
S75	241	((GOF\$1 (best\$1fit\$3) (goodness with fit\$3)) with (monitor\$3 control\$3)) and (measur\$4 and device\$1)	US-PGPUB ; USPAT; USOCR	OR	ON	2007/03/14 11:53
S76	19	((GOF\$1 (best\$1fit\$3) (goodness with fit\$3)) with (monitor\$3 control\$3)) same (measur\$4 and device\$1)	US-PGPUB ; USPAT; USOCR	OR '	ON	2007/03/14 11:54
S77	215178	((goodness near fit\$3) (curve near fitt\$3) (fitt\$3 nearl goodness) (foodness near2 measur\$4)) same ((control\$3 near limit\$1) (threshold nearl controL\$3) (control\$3 near threshold) (limit\$3 near value\$1))	US-PGPUB ; USPAT; USOCR	OR	ON	2007/03/14 11:54
S79	1	"20050027476"	US-PGPUB ; USPAT; USOCR	OR	ON	2007/03/15 15:09
S80	1	S79 and (test\$1 near site\$1)	US-PGPUB ; USPAT; USOCR	OR	ON	2007/03/15 15:17
S81	1	(linear with fit\$3 with regression\$3) and (test\$1 with site\$1) and wafer and (process\$3 near control\$3)	US-PGPUB ; USPAT; USOCR	OR	ON	2007/03/15 15:18
S82	25	(linear with fit\$3 with regression\$3) and (test\$1 with site\$1) and (process\$3 near control\$3)	US-PGPUB ; USPAT; USOCR	OR	ON	2007/03/15 15:20
S83	4	(("6.403,389") or ("5,627,101") or ("5.987,398") or ("5,883.437") or ("6.466,038") or ("5,514,974") or ("6,087,189") or ("5,552, 718")).PN.	US-PGPUB ; USPAT; USOCR	OR	OFF	2007/03/15 15:20

S84	8	(("6403389") or ("5627101") or ("5987398") or ("5883437") or ("6466038") or ("5514974") or ("6087189") or ("5552718")).PN.	US-PGPUB ; USPAT; USOCR	OR	OFF	2007/03/15 15:21
S85	28	("3335340" "3974443" "4445180" "4516071" "4560583" "4722154" "4871962" "4972248" "5010029" "5561373" "5719495" "5793471" "5854097" "5857258" "5883437" "5933020" "5963784" "6019850" "6022750" "6028440" "6087189" "6291254").PN. OR ("6403389").URPN.	US-PGPUB ; USPAT; USOCR	OR	ON	2007/03/15 15:32
S86	1	S80 and (device\$1 near screen\$3)	US-PGPUB ; USPAT; USOCR	OR	ON	2007/03/15 15:32
S87	1	("6403389").PN.	US-PGPUB ; USPAT; USOCR	OR	OFF	2007/03/15 16:21
S88	0	S87 and (test\$1 and site\$1)	US-PGPUB ; USPAT; USOCR	OR	ON	2007/03/15 15:41
S89	1	S87 and structure\$1	US-PGPUB ; USPAT; USOCR	OR	ON	2007/03/15 15:51
S90	127	(wafer\$1 near defect\$1)with (screen\$3 monitor\$3)	US-PGPUB ; USPAT; USOCR	OR	ON	2007/03/15 15:51
S91	0	((wafer\$1 near defect\$1)with (screen\$3 monitor\$3)) same (fit\$3 and curve\$1)	US-PGPUB ; USPAT; USOCR	OR	ON	2007/03/15 15:52
S92	7	((wafer\$1 near defect\$1)with (screen\$3 monitor\$3)) and (statistic\$3 with process\$3 with control\$3)	US-PGPUB ; USPAT; USOCR	OR	ON	2007/03/15 17:53
S93	0	((wafer\$1 near defect\$1)with (screen\$3 monitor\$3)) and (statistic\$3 with process\$3 with control\$3) and (test\$1site\$1)	US-PGPUB ; USPAT; USOCR	OR	ON	2007/03/15 17:54

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S94	0	((wafer\$1 near defect\$1)with (screen\$3 monitor\$3)) and (statistic\$3 with process\$3 with control\$3) and (test with site\$1)	US-PGPUB ; USPAT; USOCR	OR	ON	2007/03/15 17:54
S95	0	((wafer\$1 near defect\$1)with (screen\$3 monitor\$3)) and (statistic\$3 with process\$3 with control\$3) and (ATE)	US-PGPUB ; USPAT; USOCR	OR	ON	2007/03/15 . 17:54
S96	1	((wafer\$1 near defect\$1)with (screen\$3 monitor\$3)) and (statistic\$3 with process\$3 with control\$3) and (ATE tester\$1)	US-PGPUB ; USPAT; USOCR	OR	ON	2007/03/15 17:55
S97	1	((wafer\$1 near defect\$1)with (screen\$3 monitor\$3)) and (statistic\$3 with process\$3 with control\$3) and (ATE testers)	US-PGPUB ; USPAT; USOCR	OR	ON	2007/03/15 17:57
S98	38	(wafer\$1 with tester\$1) same (process\$3 with evaluat\$3)	US-PGPUB ; USPAT; USOCR	OR	ON	2007/03/15 17:58
S99	0	(wafer\$1 with tester\$1) same (process\$3 with evaluat\$3) same (statistic\$3 with (fit\$3 GOF best\$1fit\$3))	US-PGPUB ; USPAT; USOCR	OR	ON	2007/03/15 17:58
S10 0	18	(wafer\$1 with tester\$1) same (process\$3 with evaluat\$3) same screen\$3	US-PGPUB ; USPAT; USOCR	OR	ON	2007/03/15 18:00
S10 1	8	(wafer\$1 with tester\$1) same (process\$3 with evaluat\$3) same screen\$3 and (control\$3 with process\$3)	US-PGPUB ; USPAT; USOCR	OR	ON	2007/10/29 11:27
S10 2	1	("6217651").PN.	US-PGPUB ; USPAT; USOCR	OR .	OFF	2007/10/26 16:25
S10 3	2118	(702/109,110,57,58,117).CCLS.	US-PGPUB ; USPAT; USOCR	OR	OFF	2007/10/26 16:26
S10 4	858	(700/109,110).CCLS.	US-PGPUB ; USPAT; USOCR	OR	OFF	2007/10/26 16:26
S10 5	430	(324/716,718).CCLS.	US-PGPUB ; USPAT; USOCR	OR	OFF	2007/10/26 16:26

S10 6	47	(curve near fitt\$3) and (process\$3 with (control\$3 monitor\$3)) and (detect\$3 with defect\$1) and ((goodness nearl (fit\$4 measur\$3)) (coefficient\$1 near correlation\$1)) and (sheet\$1 near (resistance resistivity))	US-PGPUB ; USPAT; USOCR	OR	ON .	2007/10/26 16:54
S10 7	1	S106 and S103	US-PGPUB ; USPAT; USOCR	OR	ON	2007/10/26 16:55
S10 8	1	"20050027476"	US-PGPUB ; USPAT; USOCR	OR	ON	2007/10/26 16:56
S10 9	.37,457	("700").CLAS.	US-PGPUB ; USPAT; USOCR	OR	OFF	2007/10/29 11:12
S11 0	133895	("438").CLAS.	US-PGPUB ; USPAT; USOCR	OR	OFF	2007/10/29 11:12
S11 1	. 8	(wafer\$1 with tester\$1) same (process\$3 with evaluat\$3) same screen\$3 and (control\$3 with process\$3)	US-PGPUB ; USPAT; USOCR	OR	ON	2007/10/29 11:28
S11 2	1	S111 and (S109 S110)	US-PGPUB ; USPAT; USOCR	OR	ON	2007/10/29 11:28
S11 3	23	(curve near fitt\$3) and (process\$3 with (controL\$3 monitor\$3)) and (detect\$3 with defect\$1) and (goodness near fit\$4)	US-PGPUB ; USPAT; USOCR	OR	ON	2007/10/29 11:28
S11 4	0	S113 and (S109 S110)	US-PGPUB; ; USPAT; USOCR	OR	ON	2007/10/29 11:28
S11 5	0	((wafer chuck\$1 workpiece\$1) with (test\$3 near condition\$3)) and ((curve\$1 near fit\$3)) and ((process\$3 control\$3 monitor\$3) with (defect\$1))	US-PGPUB ; USPAT; USOCR	OR	ON	2007/10/29 11:43

S11 6	1	"20050027476"	US-PGPUB; USPAT; USOCR	OR	ON	2007/10/30 11:56
S11 7	2596	(438/14).CCLS.	US-PGPUB ; USPAT; USOCR	OR	OFF	2007/10/30 11:57
S11 8	7444	(wafer\$1 chuck\$1piece\$1 workpiece\$1) same (defect\$3 with (detect\$3 control\$3 monitor\$3))	US-PGPUB ; USPAT; USOCR	OR	ON .	2007/10/30 12:10
S11 9	11378	((test\$3 near condition\$1) with (temperature\$1 intensity light\$3)) and2	US-PGPUB ; USPAT; USOCR	OR	ON	2007/10/30 12:48
S12 0	37	((test\$3 near condition\$1) with (temperature\$1 intensity light\$3)) and S118	US-PGPUB ; USPAT; USOCR	OR	ON	2007/10/30 13:14
S12 1	1	S117 and S120	US-PGPUB ; USPAT; USOCR	OR	ON	2007/10/30 13:14